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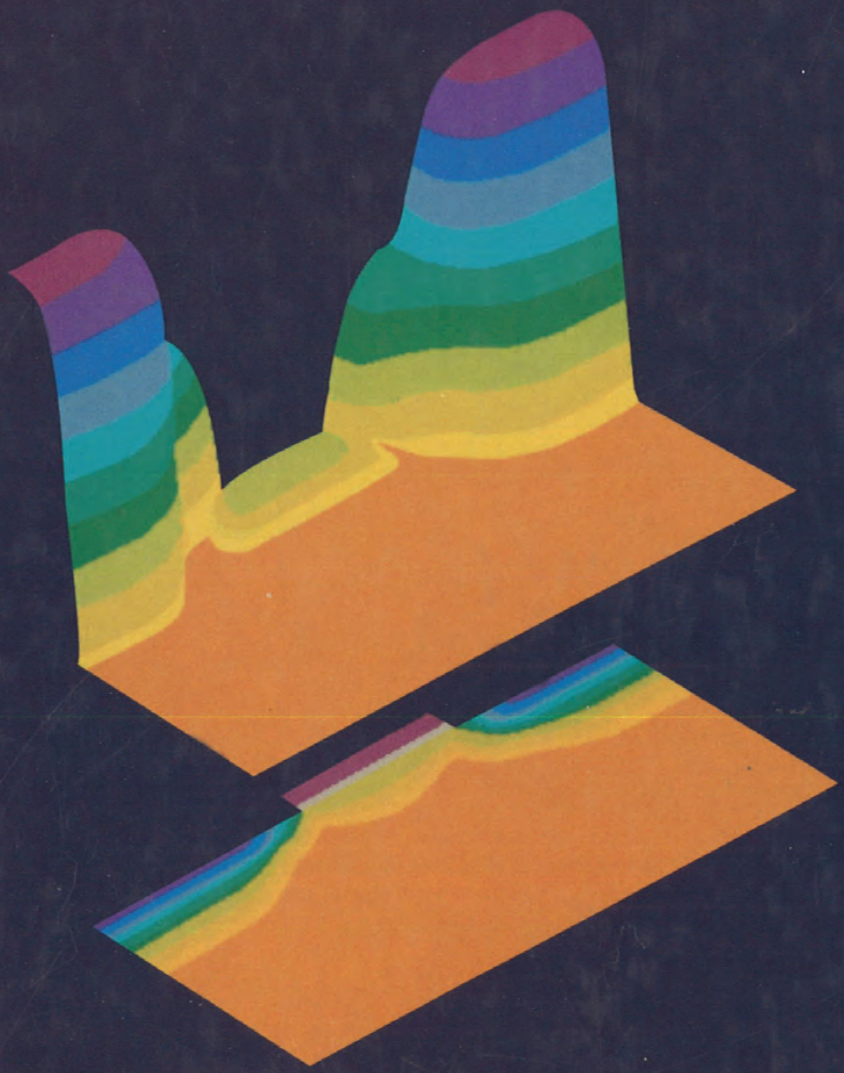
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By STANLEY WOLF and RICHARD N. TAUBER

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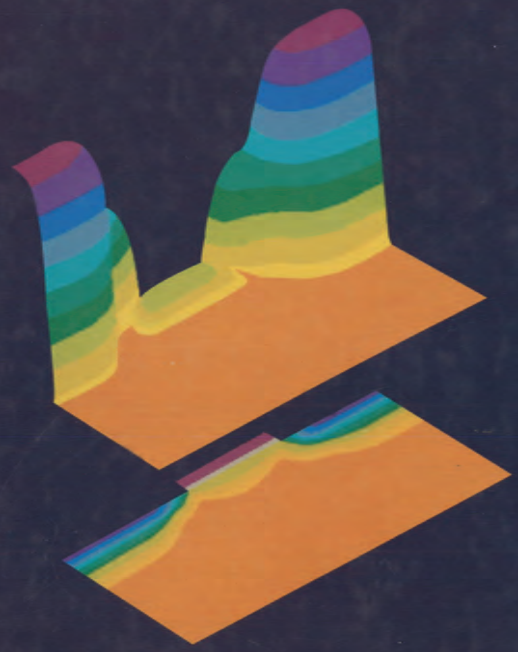
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Volume 3
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Page 6

SILICON PROCESSING

FOR

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VOLUME 3:

THE SUBMICRON MOSFET

STANLEY WOLF Ph.D.
Professor, Department of Electrical Engineering
California State University, Long Beach
Long Beach, California

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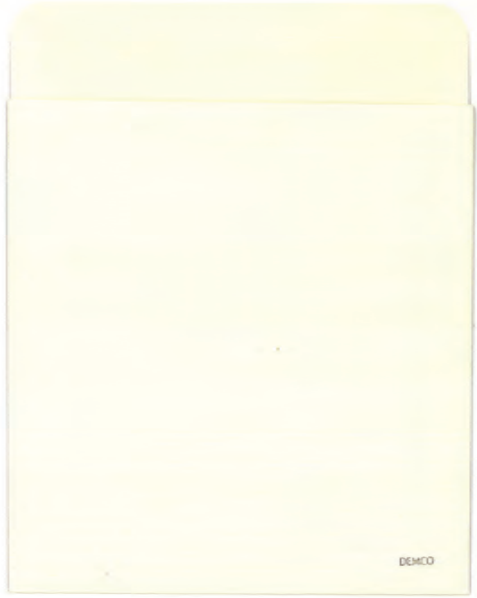
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Item policy	general (book)
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Is magnetic	No
PO Line	
Issue date	-
Receiving date	02/12/2002
Expected receiving date	-
Enumeration A	3
Enumeration B	-
Chronology I	-
Chronology J	-
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Pieces	1
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Receiving operator	import
Physical condition	-
Process type	

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Inventory date	-
Inventory price	-

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Source (Subfield 2)	-
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Item is in temporary location	**No**
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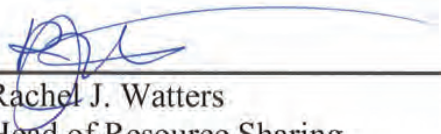
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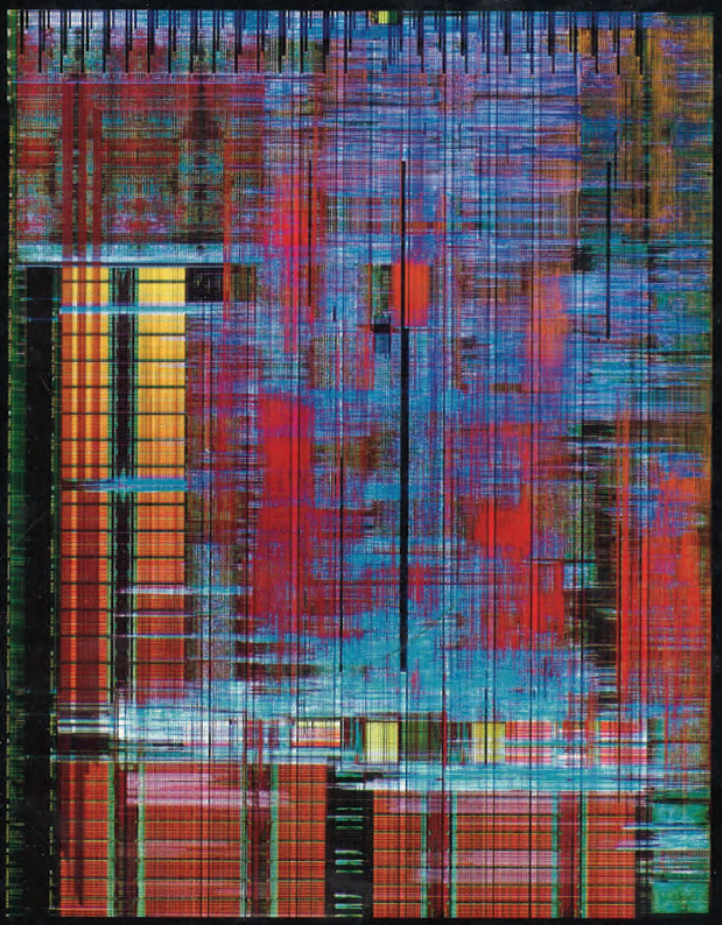
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BEN G. STREETMAN ▪ SANJAY BANERJEE

Prentice Hall Series in Solid State Physical Electronics, Nick Holonyak, Jr., Series Editor

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This is the fifth edition of the most widely used introductory book on semiconductor materials physics, devices and technology. Previous editions have been translated and Polish. The book was written with two basic goals in mind: 1) develop t physics concepts to understand current and future devices; 2) provide a sou of current semiconductor devices and technology so that their applications optoelectronic circuits and systems can be appreciated.

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- extensive discussion of circuit and other application examples to provide students with feedback about the practical relevance of the theory.
- completely updated discussion of MOS devices, both in the underlying theory as well as discussion of short channel, high field and hot carrier effects in scaled MOSFETs, recognizing the current preponderance of CMOS.
- updated, consolidated treatment of optoelectronic devices, including sources such as blue GaN-based LEDs and semiconductor vertical-cavity surface-emitting lasers, as well as detectors such as avalanche and resonant-cavity photodiodes.
- includes a listing of the key equations for semiconductor devices on the inside covers of the book, arranged thematically to help students digest the concepts.
- about 200 problems and current references which extend concepts in the text.



BEN G. STREETMAN is Dean of the College of Engineering at The University of Texas at Austin and holds the Dula D. Cockrell Centennial Chair in Engineering. He is a Professor of Electrical and Computer Engineering and was the founding Director of the Microelectronics Research Center. He has taught at the University of Illinois at Urbana-Champaign as well as the University of Texas at Austin. He has received numerous awards including the Education Medal of IEEE, The Frederick Emmons Terman Medal of the ASEE, and membership in the National Academy of Engineering. He has published more than 270 articles in the technical literature. Thirty-three students of Electrical Engineering, Materials Science, and Physics have received their Ph.D.s under his direction.



SANJAY BANERJEE is the Cullen Trust Endowed Professor of Electrical and Computer Engineering, and Director of the Microelectronics Research Center at The University of Texas at Austin. He has more than 225 archival refereed publications and 12 U.S. patents, and has supervised 18 Ph.D. students. His honors include the NSF Presidential Young Investigator Award (1988), the Texas Atomic Energy Centennial Fellowship (1990-1997), Distinguished National Lecturer for the IEEE Electron Devices Society (1997-), and Fellow of the IEEE (1996).

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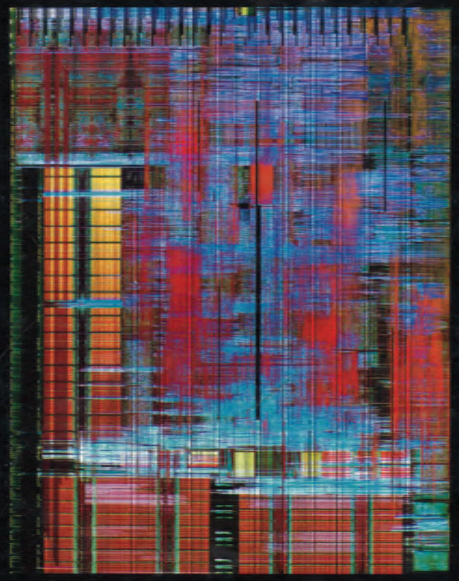


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Solid State Electronic Devices

BEN G. STREETMAN AND SANJAY BANERJEE

Microelectronics Research Center
Department of Electrical and Computer Engineering
The University of Texas at Austin



PRENTICE HALL
Upper Saddle River, New Jersey 07458

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Enumeration A	
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Item is in temporary location No Yes

Temporary location

Temporary call number type

Temporary call number

Temporary source (Subfield 2)

Temporary item policy

Due back date

Retention Information

Committed to Retain No Yes

Retention Reason

Retention Note

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